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THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: KATSUMATA et al.

Atty. Dkt.: 01-570

Serial No.: 10/791,762

Art Unit: 2812

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Examiner: TSAI

Title: METHOD OF MANUFACTURING
SEMICONDUCTOR PRESSURE SENSOR

Commissioner for Patents
U.S. Patent and Trademark Office
220 20th Street S.

Date: 28 October 2004

Customer Window, Mail Stop Amendment
Crystal Plaza Two, Lobby, Room 1B03
Arlington, VA 22202

AMENDMENT UNDER 37 CFR 1.111

Sir:

In response to the office action mailed 28 October 2004, please consider as follows:

Amendments to the Claims are reflected in the listing of claims that begins on page 2 of this paper.

Remarks begin on page 5 of this paper.